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Numerical Simulation of Microwave MESFETs in 4H-SiC Fabricated Using Epitaxial Layers on Semi-Insulating Substrates

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We present results of the numerical simulation of advanced SiC microwave devices. The high breakdown voltage and high thermal conductivity coupled with high carrier saturation velocity allow SiC microwave devices to handle much higher power densities than their silicon or GaAs RF counterparts. A variety of microwave devices with impressive DC and RF performance including MESFETs (MEtal Semiconductor Field-Effect Transistors), SITs (Static-Induction Transistors), and HBTs (Heterojunction Bipolar Transistors) have been demonstrated and these devices are developed for microwave power amplifier and oscillator applications [1]. The numerical investigation of a MESFET in 4H-SiC fabricated using epitaxial layers on semi-insulating substrate shown in Fig. 1 was performed. The key parameters that alter the overall device performance (Table 1) including the extrinsic and intrinsic elements have been optimized using the general-purpose device simulator MINIMOS-NT [2]. For the calibration of the simulator the specifications obtained from Cree's CRF-24010 4H-SiC MESFET [3] are used.

The simulated and measured DC IV characteristics are compared in Fig. 2. Excellent agreement between the simulated and measured data were obtained. This MESFET produces a maximum channel current of about 250 mA/mm. The ability of the gate bias to turn the device off and on is good, as indicated by the channel current with zero and high reverse gate bias applied. The ability of the device to modulate the current is given by the device transconductance which for this device is about $g_{\rm m}{=}160\,{\rm mS/mm}$. The zero gate voltage drain current at $V_{\rm DS}=10\,{\rm V}$ is 0.42 A/mm. This device has a drain source breakdown voltage of 110 V with a leakage current of $1\,\mu{\rm A/mm}$ as depicted in Fig. 3. Since a good agreement is obtained between both the measured and simulated DC performance, the simulator can be used for a variety of purposes. Small-signal AC simulation is conducted for the frequency range from 100 MHz to 40 GHz to determine the desired small signal RF characteristics of 4H-SiC MESFET. The measured and simulated S-parameters for this device are depicted in Fig. 4. Very good agreement between the simulated and measured data was obtained. It is important to note that the RF results presented here were obtained at a high drain-to-source bias voltage of 40 V and gain-to-source voltage of -9 V.

Other important performance figures of merit for RF devices are extracted from the S-parameter values: the cut-off frequency $f_{\rm t}$, the maximum frequency $f_{\rm max}$, the unilateral power gain (Masson's gain, U), the maximum available gain (MAG), and the maximum stable gain (MSG). The $f_{\rm t}$ (unity current gain frequency) can be calculated by extrapolation of the short circuit current gain parameter H_{21} . The value of $f_{\rm max}$ can be determined from the MAG and MSG. The small-signal current and power gain shown in Fig. 5 yields an $f_{\rm t}=5.62\,{\rm GHz}$ and $f_{\rm max}=37.18\,{\rm GHz}$ at 0 dB H_{21} and MAG/MSG, respectively. This device produced 15 dB at 1 GHz. These results clearly demonstrate the advantages of 4H-SiC for high-power microwave application where its high-thermal conductivity, high-voltage, and high-power density capability are very attractive.

REFERENCES

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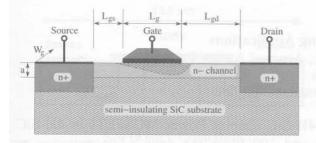


Figure 1: Cross section of 4H-SiC MESFET.

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Figure 2: Comparison of measured and simulated DC IV characteristics of a 4H-SiC MESFET.

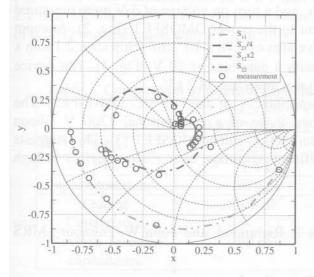


Figure 4: Comparison of measured and simulated S-parameters in a 4H-SiC MESFET.

parameter	value $0.5 \mu \mathrm{m}$			
gate length $L_{\rm g}$				
gate width $W_{\rm g}$	1 mm			
source-drain spacing	$2\mu\mathrm{m}$			
channel doping $N_{\rm d}$	$5 \times 10^{17} \ {\rm cm}^{-3}$			
channel thickness a	$0.15\mu\mathrm{m}$			

Table 1: Optimized device parameters.

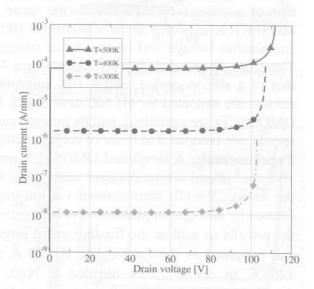


Figure 3: Reverse bias characteristics of a 4H-SiC MESFET.

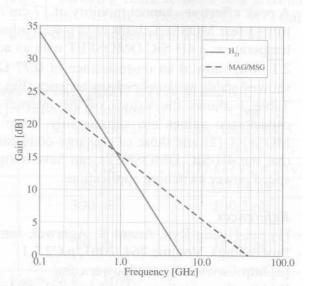


Figure 5: Small-signal current and power gain for an optimized 4H-SiC MESFET.